

UNIT CONTROL PANEL, SUBSTRATE TRANSFER TEST METHOD, AND
SUBSTRATE PROCESSING APPARATUS

ABSTRACT

PROBLEM

It is an object of the embodiment of the invention to enhance the work efficiency of a substrate transfer test between a plurality of units.

MEANS FOR SOLVING

A test control section (CPU) which is provided in a loading/unloading unit 2 performs a substrate transfer test for the loading/unloading unit 2 alone by receiving a wafer mounted on a substrate table 2300 or 2400 which is installed outside the loading/unloading unit 2 and transporting the wafer into the loading/unloading unit 2 by a transport mechanism or transporting a wafer placed in the loading/unloading unit 2 to a substrate table 2200 and mounting the wafer on the substrate table 2200 by the transport mechanism while the loading/unloading unit 2 is not assembled together with the cleaning unit and the polishing unit.

SELECTED DRAWING FIG. 8